# Semiconductor surface plasmons: a route to terahertz waveguides and sensors 



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A thesis submitted for the degree of
Doctor of Philosophy
March 2012

# Semiconductor surface plasmons: a route to terahertz waveguides and sensors 

Submitted by Edmund Keith Stone to the University of Exeter as a thesis for the degree of Doctor of Philosophy in Physics<br>2012

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I certify that all material in this thesis which is not my own work has been identified and that no material has previously been submitted and approved for the award of a degree by this or any other University.

I would like to dedicate this thesis to Phyllis Mary Hamblen my loving gran who passed away during my second year.

## Acknowledgements

During my time at Exeter many people have helped me, kept me sane and fed the insanity, all of which seem to be required for completing a PhD. To all those people, thank you. Lots are listed below, those who are not, I am sorry.

A special thank you must be said to my supervisor. Euan's enthusiasm for science is unshakable and affects all those around him. Even when the list of failed attempts appeared unending he was still positive. On a similar note, Professor Roy Sambles, thank you for suggesting my name to Euan and for your help in group meetings. Without my first summer project with you I'm not sure I would be writing a thesis currently. Tom Isaac, I am indebted to for teaching me all he knew about terahertz spectroscopy. Tom, the lock-in amplifier still only works if you catch it off guard when switching it on. During my time I have become more worried about the apparent sentience of some of our equipment.

I'd like to thank Professor Bill Barnes for many useful meetings whether it was 'back to basics,' terahertz or generation orientated. Always happy, and friendly with an insightful comment on the subject at hand. A great contributor to those early meetings was Baptiste, who along with Martin, Tim A, Tim T, John, Joe and Steph showed me just how interesting a PhD could be during my summer projects as an undergraduate. Others from the group who have moved on, Chris Burrows and James Parsons, you guys helped a lot with HFSS. James, your antics in the basement are still the topic of discussion, soon I feel the stuff of legend. Not forgetting Andy and George, your knowledge of the FIB and SEM was indispensable.

Matt L and Ian, as much as you might not like to admit it, you are both full of knowledge and happy to spread it about and help people, and between the unreproducible comments the discussions are nearly always useful. Two fellow terahertz spectroscopers, thanks for all your help Dmitry and Rostislav.

Matt B, Helen and Liz, since being undergrads together it's always been good to have a chat with you guys. Mel, thanks for helping me with maths when I hit a brick wall, even when the questions were ridiculously simple and I'd argued myself into a hole. It was always a pleasure helping you with your computer woes. Also, Mel, thanks for talking me through the panic, you'll be a great teacher! Celia, you should probably be mentioned several times in this section but tough. Thank you for all the talks, whether physics or unrelated, both at network and in uni you have always been a help and had
sensible words of advice. Tim 'starkles' Starkey, you are a unique individual, whether you're fighting with HFSS or looking confused at experiments it's always interesting. I'd like to thank the other members of the electromagnetics group who I've not named specifically and also the guys in other groups who've been good to talk to especially graphene about fabrication issues. On that note Pete Hale and Sam Hornett, two more of Euan's students who have a wealth of knowledge and are happy to pass it on when it's needed. And of course the workshop guys, Nick Cole especially, with Pete Cann, and Adam and Dave for finding me Helium when I was desperate to get some experiments done before the laser moved to its new home.

I did some demonstrating whilst doing my PhD, second year labs would not have been the same if it were not for Martin Smith, Lee Summers, and Steve Hubbard (and others mentioned in other places here), thank you guys for keeping me sane, especially you Lee, if the astro doesn't work out you can always be a stand up.

There are several people who might be thinking they have been forgotten at this point, but a special mention has to go with those of us who spend our time in the basement of physics. Alfie, you are annoyingly funny, despite your similarities to Holmes. Steve, thanks for the discussions especially recently. Matt N, you missed the best times in the basement, sorry about that. Tom C, having you in the same office has been useful for someone to bounce ideas off, I hope I've helped you in the same way. Your proof reading of some of the chapters below was indispensable, thank you. Finally for physics, Caroline and Chris 'CJ' 'Holmesey' Holmes. I have spent most of the last 4 years with you guys. There is so much to say, the arguing, the word game, the list is pretty long. Thank you. Chris, you annoyed me greatly at some points, earthquakes, and using me as a drum kit are two things that spring to mind. But despite that you are a great friend and someone who I hope I do not lose contact with. Likewise Caroline, there are many things that could go here, none of which you would like me to write, I therefore will not. Just a heartfelt thank you, finish soon, we never did find the time to play a game of mini golf. I think that pretty much completes the list of people from physics, if I've missed you, sorry.

Outside physics there are a group of people who have helped keep me routed. Helped distract me when I've needed it and helped me get to this point in my life. My parents of course, they have always believed in me and supported me through everything I have done. If it was not for the way they have brought me up I do not know where I would be at this point. I should also thank my brother, Tris, for constantly suggesting I could wear things as a special hat. When Celia first met Tris, she was surprised as from when I talked about him she had assumed I was the older brother.

Some friends and influences from other places have also enabled me to get to this point. Friends from scouting, especially James and Matt, two of my oldest friends who
are always good for a distraction. And Mr Bushrod, a great inspiration, my first real science teacher when I was around 9 years old, he inspired me to find out how the world worked with some truly great teaching.

Lastly, Sarah, thank you for being honest and for being there, when discussing me day with you, you always listened and then pointed out you didn't know what I was talking about. And of course thank you for making me some amazing food, your cheesecake is just fantastic.


#### Abstract

The terahertz regime has until recently been some what neglected due to the difficulty of generating and measuring terahertz radiation. Terahertz time domain spectroscopy has allowed for affordable and broadband probing of this frequency regime with phase sensitive measurements (chapter 3). This thesis aims to use this tool to add to the knowledge of the interactions between electromagnetic radiation and matter specifically in regard to plasmonics.

This thesis covers several distinct phenomena related to plasmonics at terahertz frequencies. The generation of terahertz radiation from metal nanoparticles is first described in chapter 4. It is shown that the field strength of the plasmon appears to relate to the strength of the generated field. It is also shown that the power dependence of the generated terahertz radiation is not consistent with the optical rectification description of this phenomenon. An alternative explanation is developed which appears more consistent with the observations. A simple model for the power dependence is derived and compared to the experimental results.

In chapter 5 the parameters that make good plasmonic materials are discussed. These parameters are used to assess the suitability of semiconductors for terahertz surface plasmon experiments. The Drude permittivity of InSb is measured here, leading to a discussion of terahertz particle plasmons in chapter 6. Finite element method modelling is used to show some merits of these over optical particle plasmons. This also includes a discussion of fabrication methods for arrays of these particles.

Finally, chapter 7 is a discussion of so called spoof surface plasmons. This includes some experimental work at microwave frequencies and an in depth analysis of open ended square hole arrays supported by model matching method modelling. Perfect endoscope effects are discussed and compared to superlensing. The thesis ends with a brief conclusions chapter where some of the ideas presented are brought together.


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## Definitions

| FEM | Finite element method |
| :--- | :--- |
| FIB | Focussed ion beam |
| InSb | Indium antimonide |
| SEM | Scanning electron microscope |
| SPP | Surface plasmon polariton |
| TE | Transverse electric (s-polarised) |
| THz-TDS | Terahertz time domain spectroscopy |
| TM | Transverse magnetic (p-polarised) |
|  |  |
| Microwave regime | $1 \rightarrow 200 \mathrm{GHz}$ |
| Optical/Visible regime | $300 \rightarrow 1000 \mathrm{THz}$ |
| Terahertz regime | $0.2 \rightarrow 2 \mathrm{THz}$ |

